



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
PETITION FOR EXTENSION OF TIME FROM THE OFFICE ACTION

*I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on October 23, 2008.*

Shannon L. Stewart

Applicant : Kim, Nam Hun  
Application No. : 10/593,857  
Filed : September 22, 2006  
Title : PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND  
METHOD FOR ETCHING THE WAFER USING THE SAME

Confirmation No. 5813

Grp./Div. : 1792  
Examiner : Duy Vu Nguyen Deo  
Docket No. : 58409/N305

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Post Office Box 7068  
Pasadena, CA 91109-7068  
October 23, 2008

Commissioner:

Applicant petitions the Commissioner to extend the time for response to the Office action dated June 23, 2008 for one month(s) from September 23, 2008 to October 23, 2008.

The fee for extension of time required by 37 CFR § 1.17 is calculated below.

FEE CALCULATION			
LENGTH OF EXTENSION	SMALL ENTITY	LARGE ENTITY	FEE
WITHIN FIRST MONTH	\$ 65.00	\$ 130.00	\$65.00

Submitted herewith is a check for \$65.00 to cover the cost of the extension.

The Commissioner is hereby authorized to charge any fees under 37 CFR 1.16 and 1.17 which may be required by this paper to Deposit Account No. 03-1728. Please show our docket number with any charge or credit to our Deposit Account. **A copy of this letter is enclosed.**

Respectfully submitted,  
CHRISTIE, PARKER & HALE, LLP

By

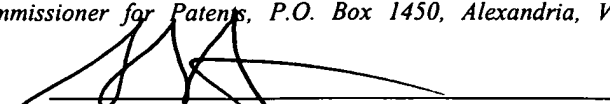
Peter C. Hsueh  
Reg. No. 45,574  
626/795-9900



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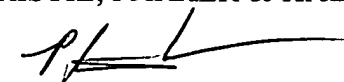
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